



Quantitative investigation of point defects and their dynamics in focused ion beam-prepared group III-nitride lamellas by off-axis electron holography

Keyan Ji

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Contents

1	Introduction	7
2	Theoretical background and experimental details	11
2.1	Transmission electron microscope: Theoretical background	11
2.1.1	Parallel illumination vs. scanning mode	12
2.1.2	Electron holography	13
2.1.3	High angle annular dark field imaging	19
2.1.4	Energy dispersive X-ray spectroscopy	22
2.1.5	Convergent electron beam diffraction	24
2.2	Experimental details	25
2.2.1	Lamella preparation	25
2.2.2	Lamella crystalline thickness determination	27
2.2.3	Electron holography	28
2.2.4	STEM and EDX: Strain and chemical composition measurement	32
2.3	Sample description	33
2.3.1	A3162	33
2.3.2	A3777	34
3	FIB damage and its implication for quantification of electron holographic results	37
3.1	FIB damage types and sub-layers	37
3.1.1	Amorphous outer shell	38
3.1.2	Defect-rich crystalline inner shell	39
3.2	Previous handling of FIB damaged (dead) layers	46
3.3	Simulation of the electron holography results	50
3.3.1	Modelling of surface Fermi-level pinning: Case of III-nitride	51
3.3.2	Self-consistent electrostatic potential calculation	56
3.3.3	From electrostatic potential to electron optical phase	64
4	Electrostatic versus diffraction contribution to electron holography: An experimental approach	67
4.1	Overview	67
4.2	Results	67

4.3	Discussion	71
4.4	Summary	72
5	Origin of phase contrast of modulation-doped GaN	75
5.1	Overview	75
5.2	Results	75
5.3	Discussion	78
	5.3.1 Origin of the phase contrast across the GaN doping step . .	78
	5.3.2 Comparison with <i>n</i> -type GaN structures from references . .	81
5.4	Summary	82
6	Quantification of surface effect: Fermi-level pinning by substitutional C	83
6.1	Overview	83
6.2	Results	83
	6.2.1 Single-cycle in-situ annealing	83
	6.2.2 Two-cycle in-situ annealing	84
	6.2.3 Ambient exposure and electron beam irradiation	87
	6.2.4 Self-consistent electrostatic potential calculation: Surface Fermi-level pinning	88
6.3	Discussion	91
	6.3.1 Type of FIB-implanted point defect	91
	6.3.2 Implantation of C _N by FIB	93
	6.3.3 Discussion of the healing process	95
6.4	Summary	96
7	Thermal dynamics of Fermi-level pinning: Substitutional C site switching	99
7.1	Overview	99
7.2	Electron holography results	99
7.3	Data analysis	103
	7.3.1 Time constant analysis	103
	7.3.2 Derivation of activation barrier and diffusion length	104
7.4	Discussion	107
7.5	Summary	108
8	A demonstration on quantification of phase map: Case of (Al,In)N/GaN interface	111
8.1	Overview	111
8.2	Results	111
	8.2.1 Electron holography	111
	8.2.2 High resolution STEM	112

8.3	Self-consistent electrostatic potential calculation	119
8.3.1	Relevant fixed parameters	119
8.3.2	Effect of mean inner potential	120
8.3.3	Effect of electron affinity and polarization	121
8.3.4	Influence of the In composition gradient in (Al,In)N on phase map	123
8.4	Discussion: Origin of the composition gradient	126
8.5	Summary	128
9	Conclusion	129
	Abstract	133
	Acronym list	137
	List of own publications	139
	Bibliography	141
	Acknowledgement	163

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Band / Volume 105

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